INFORMATION DISCLOSURE STATEMENT

Applicant : Sherman

App. No : 10/683,727

Filed : October 10, 2003

For : SEQUENTIAL CHEMICAL VAPOR

DEPOSITION

Examiner : Kelly M. Stouffer

1762

CERTIFICATE OF EFS WEB TRANSMISSION

I hereby certify that this correspondence, and any other attachment noted on the automated Acknowledgement Receipt, is being transmitted from within the Pacific Standard Time (PST) zone to the Commissioner for Patents via the EFS Web server on:

June 22, 2007

(Date)

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

Dear Sir:

Art Unit

Enclosed for filing in the above-identified application is a PTO/SB/08 Equivalent listing 3 references to be considered by the Examiner. Also enclosed are 3 foreign patent references and/or non-patent literature as listed on the Information Disclosure Statement.

This Information Disclosure Statement is being filed within three months of the filing date, with an RCE or before receipt of a first office action after an RCE and no fee is required.

The Commissioner is hereby authorized to charge any additional fees which may be required or to credit any overpayment to Account No. 11-1410.

Respectfully submitted,

KNOBBE, MARTENS, OLSON & BEAR, LLP

Dated: 6/22/07

By:_______ Zi Y. Wong

Registration No. 58,410 Attorney of Record Customer No. 20,995

(415) 954-4114

INFORMATION DISCLOSURE STATEMENT BY APPLICANT

 Application No.
 10/683,727

 Filling Date
 October 10, 2003

 First Named Inventor
 Sherman

 Art Unit
 1762

 Examiner
 Kelly M. Stouffer

 Attomey Docket No.
 ASMMC-9CP1DV1C1

(Multiple	sheets used	when	necessary)
	SHEET 1	OF 1	

			U.S. PATENT	DOCUMENTS	
Examiner Initials	Cite No.	Document Number Number - Kind Code (if known) Example: 1,234,567 B1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear

	FOREIGN PATENT DOCUMENTS					
Examiner Initials	Cite No.	Foreign Patent Document Country Code-Number-Kind Code Example: JP 1234567 A1	Publication Date MM-DD-YYYY	Name of Patentee or Applicant	Pages, Columns, Lines Where Relevant Passages or Relevant Figures Appear	T ¹

	NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No.	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ¹	
		20a-ZC-1, MIYAMOTO et al., "High-Fluidity Deposition of SiN by Cryogenic Remote Plasma CVD," Research Center for Integrated Systems and Faculty of Engineering, Hiroshima University, 1 page.	1	
		20a-ZC-2, GOTOU et al., "Atomic-Layer Deposition of SiN by Remote Plasma CVD," Research Center for Integrated Systems, Hiroshima University, 2 pages.	1	
		20a-ZC-3, NAKAMURA et al., "Atomic-Layer Deposition of SiO₂ by Remote Plasma CVD," Research Center for Integrated Systems, Hiroshima University, 1 page.	1	

3917458 062207

Examiner Signature Date Considered

*Examiner: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.